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| 個人照片<br>Personal Photo               |    |
| 姓名<br>Name                           | Chin-Chang, Yeh   |
| 職稱<br>Title                          | Assistant Professor   |
| 最高學歷<br>The Highest Education Degree | Ph.D., Department of Mechanical Engineering, National Central University  |
| 研究室<br>Office                        | 60304C  |
| 電話<br>Phone                          | 886-2-7738-0145 Ext:3132  |
| 電子郵件<br>Email                        | ccyeh@mail.oit.edu.tw   |
| 專長領域<br>Research Field               | Precision measurement technology<br>Mechanical manufacturing processing technology<br>Non-traditional manufacturing technology<br>Computer aided engineering technology<br>Mold engineering design and analysis practice<br>Product development and design  |
| 發表著作<br>Recent Publications          | <ul style="list-style-type: none"> <li>● <b>Journal Paper :</b></li> <li>1. L.D. Yang, K.L. Wu, <b>C.C. Yeh</b>, H.M. Lee, " Study on Precision Polishing Technology Combining Electrophoresis and Magnetic Finishing", International Journal of Materials Science and Applications, Vol. 5, Issue 6, pp. 235-824, 2016.</li> <li>2. <b>C.C. Yeh</b>, K.L. Wu, J.W. Lee, B.H. Yan, "Processing Characteristics using Phosphorous Dielectric on Wire Electrical Discharge Machining of Polycrystalline Silicon", Materials and Manufacturing Processes, Vol. 29, Issue 2,</li> </ul> |

pp. 146-152, 2014.

3. **C.C. Yeh**, K.L. Wu, J.W. Lee, B.H. Yan, "Study on Surface Characteristics using Phosphorous Dielectric on Wire Electrical Discharge Machining of Polycrystalline Silicon", The International Journal of Advanced Manufacturing Technology, Vol. 69, Issue 2, pp. 71-80, 2013.

● **Conference Paper :**

1. L.D. Yang, K.L. Wu, **C.C. Yeh**, H.M. Lee, " Study on Precision Polishing Technology Combining Electrophoresis and Magnetic Finishing", International Conference on Advanced Materials and Process Engineering, ICAMPE 2016.
2. K.L. Wu, S.H. Lee, J.C. Hung, **C.C. Yeh**, B.H. Yan, " Using Adjustable Magnetic Field to Enhance the Performance with Electro-Chemical Discharge Machining", International Symposium on Green Manufacturing and Applications, ISGMA 2016.
3. H.M. Lee, A.C. Wang, K.L. Wu, **C.C. Yeh**, Y.L. Wu, " Experimental Investigation on Oil and Water Mixture Slurry for Polishing by Solid and Liquid States", International Symposium on Green Manufacturing and Applications, ISGMA 2015.
4. K.L. Wu, **C.C. Yeh**, H.M. Lee, B.H. Yan, " The Effect on Polycrystalline Silicon Surface Characteristic by Electrical Chemical Machining Grinding using Graphene Oxide Suspension", International Symposium on Green Manufacturing and Applications, ISGMA 2015.
5. **C.C. Yeh**, K.L. Wu, J.W. Lee, B.H. Yan, "Study on Processing Characteristics by Using Dielectric with Phosphorous on Wire Electrical Discharge Machining Polycrystalline Silicon", 15th International Conference on Advances in Materials and Processing Technologies, AMPT 2012.
6. K.Z. Liang, **C.C. Yeh**, C.C. Chung, "The Optimal Parameters of the Water-Assisted Injection Molding Process with ABS Material", Conference at Society of Plastics Engineer, ANTEC 2005.